Amendments to the Claims:

This listing of claims will replace all prior versions, and listings, of claims in the application:

Listing of Claims:

1. (Currently Amended) An apparatus for on-demand chemical etch using a medium, the apparatus comprising:

~~a stencil web;~~

a printing mechanism that receives the medium and prints content on a surface of the medium;

an etching head mechanism; and

a ~~media~~ medium support system configured to transport the medium from the printing mechanism past a surface of the etching head. ~~; and~~

~~an etching head mechanism~~

~~wherein said stencil webtransported under said etching head mechanism by said media support system.~~

2. (Currently Amended) The apparatus of claim 1 wherein said ~~media~~ medium support system comprises a ~~stencil~~ medium unwind hub and a ~~stencil~~ medium rewind hub.

3. (Currently Amended) The apparatus of claim 1 further comprising:

~~a printing mechanism, said printing mechanism comprising a print head, a thermal transfer ribbon and~~ ribbon support system; and

a spent carrier rewind hub~~;~~, wherein the ~~web~~ medium includes a carrier liner that is wound into the spent carrier rewind hub.

~~wherein said printing mechanism is located before the etching head mechanism.~~

4. (Currently Amended) The apparatus of claim 1 wherein said etching head mechanism extends and sandwiches said ~~stencil~~ ~~web~~ medium between said etching head mechanism and a target object.

5. (Original) The apparatus of claim 4 further comprising a grounding electrode on said etching head mechanism.

6. (Previously Presented) The apparatus of claim 4 further comprising a conveyor, wherein said target object is on the conveyor and said conveyor is adapted to be actuated upwards to push the target object against the etching head.

7. (Currently Amended) The apparatus of claim 1 wherein said ~~stencil~~ ~~web~~ medium is preprinted.

8. (Original) The apparatus of claim 1 further comprising a part surface wiper.

9. (Currently Amended) The apparatus of claim 1 further comprising a handheld unit, wherein said ~~stencil~~ ~~web~~ medium, ~~media~~ said medium support system, and said etching head mechanism are adapted to be housed in said handheld unit.

10. (Currently Amended) The apparatus of claim 2 further comprising a handheld unit, wherein said ~~stencil~~ ~~web~~ medium, ~~media~~ said medium support system, and said etching head mechanism are adapted to be housed in said handheld unit.

11. (Currently Amended) The apparatus of claim 3 further comprising a handheld unit, wherein said ~~stencil~~ ~~web~~ medium, ~~media~~ said medium support system, and said etching head mechanism are adapted to be housed in said handheld unit.

12. (Currently Amended) The apparatus of claim 4 further comprising a handheld unit wherein said ~~stencil web~~ medium, ~~media~~ said medium support system, and said etching head mechanism are adapted to be housed in said handheld unit.

13. (Original) The apparatus of claim 12 further comprising a grounding electrode on said etching head mechanism.

14. (Currently Amended) The apparatus of claim 9 wherein said ~~media~~ medium support system comprises a cartridge and the stencil ~~web~~ medium is loaded in the cartridge as a stack of preprinted stencils.

15. (Currently Amended) The apparatus of claim 14 wherein the ~~media~~ medium support system further comprises a collection bin adapted to hold used stencils.

16. (Cancelled)

17. (Previously Presented) The apparatus of claim 10 wherein the etching head is replaceable.

18. (Currently Amended) A method for on-demand chemical etch comprising the steps of:

~~obtaining a stencil web; said stencil web on a media support system comprising a media unwind hub and a stencil rewind hub;~~

~~unwinding said stencil web from said stencil unwind hub;~~

transporting ~~said stencil web~~ a continuous medium under a print head;

printing data associated with a target object on the continuous medium ~~in reverse on said stencil web~~ to create a stencil;

~~peeling away a carrier from said stencil;~~

transporting ~~said stencil~~ the medium past a surface of ~~under~~ an etching head; and using the etching head to etch the data on a surface of a target object.

~~sandwiching said stencil between said etching head and an object;~~

~~applying a wetting solution;~~

~~actuating an electrode;~~

~~rewinding a spent stencil on the stencil rewind hub~~.

19. (New) An apparatus for on-demand etching, the apparatus comprising:

a medium source;

an etch head; and

a medium support system configured to transport the medium from the medium source to an operational location that is proximal to a surface of the etch head.

20. (New) The apparatus of claim 19, wherein with the medium at the operational location, the etch head uses the medium at the operational location to etch a surface of a target object.

21. (New) The apparatus of claim 19, wherein the medium source comprises a hub, the hub configured to receive a roll of the medium and configured to have the roll of medium unwound therefrom.

22. (New) The apparatus of claim 19, wherein the medium support system comprises a rewind hub configured to have the medium wound thereon.

23. (New) The apparatus of claim 19, wherein the medium source comprises a cartridge having a plurality of media stacked therein.

24. (New) The apparatus of claim 19, further comprising:

a print system interposing the medium source and the etch head, the print system being continuously feed with the medium by the medium support system and printing on a surface of the medium.

25. (New) The apparatus of claim 24, wherein the print system comprises a thermal print head.

26. (New) The apparatus of claim 19, further comprising:

a release liner hub configured to wind a release liner.

27. (New) The apparatus of claim 19, wherein the medium source is configured to continuously feed the medium to the etch head.

28. (New) The apparatus of claim 27, wherein the medium comprises a continuous roll of a mesh material.

29. (New) The apparatus of claim 19, wherein the medium source comprises a medium loader configured to load the medium into the apparatus one at a time.

30. (New) An apparatus for on-demand chemical etching, the apparatus comprising:

a medium loader configured to load a medium into the apparatus one medium at a time;

an etch head configured to receive the medium; and

a medium support system that feeds of the medium from the medium loader to a location that is proximal to a surface of the etch head.

31. (New) The apparatus of claim 30, wherein the medium received by the medium loader comprises a mesh having a surface, the surface having content printed thereon.

32. (New) The apparatus of claim 30, wherein the medium received by the medium loader comprises a mesh having a surface, the surface having content printed thereon.